

Electronic Patent Application Fee Transmittal

Application Number:	10586788			
Filing Date:	02-Sep-2008			
Title of Invention:	PLASMA EXCITED CHEMICAL VAPOR DEPOSITION METHOD SILICON/ OXYGEN/NITROGEN-CONTAINING-MATERIAL AND LAYERED ASSEMBLY			
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Attorney Docket Number:	INF 2006 VJ 33543 US			
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Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Basic Filing:				
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Claims:				
Miscellaneous-Filing:				
Petition:				
Patent-Appeals-and-Interference:				
Post-Allowance-and-Post-Issuance:				
Utility Appl issue fee	1501	1	1510	1510
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Total in USD (\$)				1810